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PATENT & TRADEMARK OFFICE

INFORMATION DISCLOSURE CITATION PTO-1449	ATTY. DOCKET NO. SNPS-0524	APPLICATION NO. 10/683,534
	APPLICANT Lawrence S. Melvin III	
	FILING DATE October 10, 2003	GROUP ART UNIT 2123

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation Yes	Translation No
APL	WO 01/42964 A2	14 June 2001	PCT	G06F 17/00			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

APL	Publication entitled "A Model-Based Methodology for Reducing OPC Output Pattern Complexity", by Lawrence S. Melvin III, Proceedings of SPIE, Vol. 5256, 23rd Annual BACUS Symposium on Photomask Technology, XP-002367949, Pages 238-245.
APL	Publication entitled "OPC Strategies to Minimize Mask Cost and Writing Time", by Michael L. Rieger, Proceedings of SPIE, Vol. 4562, 21st Annual BACUS Symposium on Photomask Technology, XP-002367949, Pages 154-160.
APL	Internet Article entitled "Proteus, Progen, Prospector Full-Chip Optical Proximity Correction", 14 April 2003, XP002367951, URL: http://web.archive.org/web/20030414050107/www.synopsys.com/products/avmrg/pdfs/proteus_ds.pdf.

EXAMINER	DATE CONSIDERED
	09/21/06

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449	ATTY. DOCKET NO. SNPS-0524	APPLICATION NO. To Be Assigned
	APPLICANT Lawrence S. Melvin III	
	FILING DATE October 10, 2003	GROUP ART UNIT To Be Assigned

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
APL	6,453,457	Sept. 17, 2002	Pierrat et al.	716	19	9/29/00

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation Yes	Translation No

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EXAMINER	DATE CONSIDERED
Q. K. Phan	09/21/06

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